Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claims 1-4. (Cancelled)

5. (New) A surface inspection method for inspecting a plurality of inspection subjects having films coated thereon, comprising the steps of:

storing inspection data regarding an inspection apparatus and film parameters regarding the films coated on the inspection subjects, by associating with each other, so as to obtain predetermined inspection conditions; and

automatically setting a wavelength of a laser, an incident angle, and a polarization as the predetermined inspection conditions for the inspection apparatus by selecting the film parameters of the inspection subjects to be measured in the inspection apparatus by an operator, when performing each measurement,

wherein the films coated on the inspection subjects to be measured have different thicknesses to each other, and two or more kinds of laser which emit luminance flux having different wavelengths to each other are switched or mixed to make the laser incident on the film-coated inspection subjects at a same incident angle.

6. (New) The surface inspection method according to claim 5, wherein the film parameters set by the operator include a film thickness and a refraction index.

7. (New) The surface inspection method according to claim 5, wherein only the film thickness of the inspection subject to be measured is selected, when performing each measurement.

8. (New) A surface inspection apparatus for inspecting a plurality of inspection subjects, comprising:

an inspection data storage device that is configured to store inspection data regarding an inspection apparatus and film parameters regarding films coated on the inspection subjects, by associating with each other, so as to obtain predetermined inspection conditions;

a setting device that is configured to set, by an operator, the film parameters of the inspection subjects, when performing each measurement;

an arithmetic device that is configured to automatically calculate the predetermined inspection conditions on a basis of the film parameters set by the setting device; and

a controller that is configured to control the inspection apparatus on a basis of the predetermined inspection conditions calculated by the arithmetic device,

wherein the films coated on the inspection subjects have different thicknesses to each other,

wherein the surface inspection apparatus is configured to provide two or more kinds of laser which emit luminance flux having different wavelengths to each other, wherein the surface inspection apparatus is configured to switch or mix the two or more kinds of laser to make the laser incident on the film-coated inspection subjects at a same incident angle.

9. (New) The surface inspection apparatus according to claim 8, wherein the film parameters set by the setting device include a film thickness and a refraction index.

10. (New) The surface inspection apparatus according to claim 8, wherein only the film thickness of the inspection subject to be measured is selected, when performing each measurement.

11. (New) A method of inspecting a surface of film-coated inspection subjects, comprising the steps of:

providing film parameters for a film coated on an inspection subject and storing the film parameters in an inspection apparatus;

determining inspection data for the film by performing a light inspection of the inspection subject and storing the inspection data in the inspection apparatus;

automatically selecting optimum inspection conditions, wherein the inspection conditions are determined from a correlation of the inspection data to the stored film parameters; and

performing light inspection of film-coated inspection subjects on a basis of the selected optimum inspection conditions, wherein light inspection is performed using two or more different wavelengths that are switched or mixed with one another and are incident on the film-coated inspection subjects at a same incident angle;

wherein films of the inspection subjects vary in thickness.

12. (New) The method according to claim 11, wherein the film parameters comprise film thickness and a film refraction index.

13. (New) The method according to claim 11, wherein the film parameters consist of film thickness.

14. (New) The method according to claim 11, wherein the film parameters are provided by an operator.

15. (New) The method according to claim 11, wherein inspection conditions comprise a laser wavelength, an incident angle, and a polarization.